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INFORMATION DISCLOSURE STATEMENT  (Use several sheets if necessary)		APPLICANTS Takao ABE, Teruhiko HIRASAWA, Katsushi TOKUNAGA, Tetsuya IGARASHI, Masafumi YAMAGUCHI		
		FILING DATE January 18, 2001	GROUP	
U.S. PATENT DOCUMENTS				
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME
FOREIGN PATENT DOCUMENTS				
		DOCUMENT NUMBER	DATE	COUNTRY
WMA		JP 8-259382	10/08/1996	Japan
WMA		JP 5-208892	08/20/1993	Japan
WMA		JP 64-27278	01/30/1989	Japan
WMA		JP 8-330611	12/13/1996	Japan
WMA		JP 6-169096	06/14/1994	Japan
WMA		JP 10-324592	12/08/1998	Japan
WMA		JP 7-206583	08/08/1995	Japan
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)				
WMA		EHRSTEIN, J. R. SPREADING RESISTANCE CALIBRATION FOR GALLIUM- OR ALUMINUM DOPED SILICON, 1980, J. Electrochem. Soc., Vol. 127, No 6, pp. 1403-1404.		
WMA		DENKI, KAGAKU, KYOUKAI, DENSHI, ZAIRYOU, IINKAI ED., "HANDOUTAI ZAIRYOU" July 30, 1970, p. 87 lines 6-7; p. 97, lines 16-17. <i>in Japanese</i>		
WMA		YAMAMOTO, Mikio ed., "KESSHOU KOUGAKU HANDBOOK", September 10, 1975, Kyoritsu Shuppan K. K., p. 643, left colum, line 28 to right column, line 22; Table VII 3 8		
WMA				
EXAMINER	<i>WMA Anderson</i>			DATE CONSIDERED 7/24/02
Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.				